

1. Record Nr.	UNISA996206561003316
Titolo	1997 2nd International Symposium on Plasma Process-Induced Damage : 13-14 May 1997, Monterey, California, USA
Pubbl/distr/stampa	[Place of publication not identified], : Northern California Chapter of the American Vacuum Society, 1997
Disciplina	621.3815/2
Soggetti	Semiconductor wafers - Defects Semiconductors - Effect of radiation on Plasma etching - Congresses Electrical & Computer Engineering Electrical Engineering Engineering & Applied Sciences
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	Bibliographic Level Mode of Issuance: Monograph